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Cryo-EM Workshop@NUS

General Cryo-EM References

- Glaeser, R. M., Downing, K, DeRosier, D., Chiu, W. and Frank, J. (2007) Electron Crystallography of Biological Macromolecules, Oxford University Press.
- <u>Chang J</u>, <u>Liu X</u>, <u>Rochat RH</u>, <u>Baker ML</u>, <u>Chiu W</u>. (2012). Reconstructing virus structures from nanometer to near-atomic resolutions with cryo-electron microscopy and tomography. <u>Adv Exp Med Biol</u>. **726**:49-90.
- Jensen, G. (2010) <u>Methods in Enzymology</u> <u>Volume 481</u>. Many review papers

Pipeline in Single Particle Cryo-EM

Biochemical Preparation Cryo-EM Sample Preparation High Resolution Automated Data Collection JADAS



Why CryoEM?

- Can determine structures at different chemical or biological conformation states
- Can work with large complex of mixed/dynamic conformations
- Can determine Structure that cannot be tackled readily by NMR or crystallography
- Need only low concentration (<1mg/ml) in less than 100 µl sample
- Resolution can be reached to ~3.5 Å in favorable cases

Growth of EM Entries



Courtesy of Cathy Lawson, PDB, Rutgers University

Cryo-Specimen Preparation

- Dubochet, J., Adrian, M., Chang, J.J., Homo, J.C., Lepault, J., McDowall, A.W. & Schultz, P. (1988). *Q Rev Biophys* 21, pp. 129-228.
- Taylor, K.A., and Glaeser, R.M. (2008). Retrospective on the early development of cryoelectron microscopy of macromolecules and a prospective on opportunities for the future. *J Struct Biol 163*, 214-223.
- Megan J. Dobro, Linda A. Melanson, Grant J. Jensen, Alasdair W. McDowall (2010) Plunge Freezing for Electron Cryomicroscopy. *Methods in Enzymology* 481, 63-82.



Basic Requirements for Vitrification Apparatus

1. Ambient

- low humidity & proper electrical grounded
- 2. Blotting mechanism
 - manual, pneumatic or electronic
- 3. Blotting chamber
 - high humidity
- 4. Plunging mechanism
 - high entrance velocity
- 5. Cryogen
 - high cooling efficiency



Cryo-Specimen Preparation







Courtesy Dr. Peter Frederik, University of Masstricht

Vitrification

Vitrification – immobilization of H_2O is achieved before its crystallization



- rapid cooling rate
- small mass of specimen

For pure water:

cooling rate: $10^6 \circ C/sec$ (for 1 µm thick layer)

vitrification time: $t_V = 10^{-4}$ sec

Sublimination of ice in an electron microscope ?



(a) Vapour pressure *P* in Pa as function of the temperature in °C.
(133Pa = 1 Torr; 10⁵ Pa = 1 bar = 0.987 atm)

(b) Sublimation of ice in perfect vacuum as a function of the temperature in °C.
(1 mg/m² corresponds to 1 nm thickness at a density of 1 g/cm³).

** Sublimation of vitreous ice is very small at $T \leq T_{v}$

Courtesy of Dr. J. Dubochet

Vitrified Sample in 20 mM Mops (pH 7.4), 300 mM KCl, 1 mM DTT, 0.4% CHAPS, 5% sucrose



Courtesy of Dr. I Serysheva

200 kV image of ice-embedded Ion Channel



Courtesy of Dr. I Serysheva

Radiation Damage Assessment of Protein Crystals

Record a series of 9-10 electron images or electron diffraction patterns from a single thin protein crystal (catalase crystal)

Measure quantitatively the fading of the diffraction spot intensities as a function of cumulative exposure (also known as dose)

Radiation Damage Studies of Ice Embedded Catalase Crystal



B Bammes, J Jakana, M Schmid, W Chiu JSB 169: 331-341 (2010)

Quantification of Damage

 N_e (1/e) decay dose

Dissimilarity factor

Fading of Fourier Amplitudes at different temperatures



B Bammes, J Jakana, M Schmid, W Chiu *JSB* **169**: 331-341 (2010)

Fading of Fourier Amplitudes at different temperatures





Image of a 2D protein crystal

G Ren



Electron Diffraction Pattern of a Protein 2-D Crystal

Ren & Mitra

Detector Physical Sizes

- 4x4 K CCD (16 megapixels with 15 µm pixel size)
- 10x10 K CCD (111 megapixel with 9 µm pixel size)
- 3x4 K DDD (12.6 megapixel with 6 µm pixel size)
- Photographic film



TEM CCD Architecture



Field of View and Microscope Ports



C Booth, Gatan

Magnification Factor



 Δd varies in different magnification of the scope

- <u>Resolution</u>: Simply, the ability to distinguish contrast (usually fine detail.) Often expressed in conjunction with MTF.
- <u>Sensitivity</u>: The level of (incoming) signal required to produce an intensity (output) change.
- <u>Point Spread Function (PSF)</u>: Distribution of photons from incoming electron (i.e., cloud due to random motion of electron.)
- <u>Dynamic Range</u>: Simply, the range of values that can be distinguished between a maximum level and zero (noise.) Driven by combination of full well (affected by pixel size) and noise baseline with no exposure. Can be increased with binning.
- <u>DQE (Detection Quantum Efficiency)</u>: Best "overall" measure of a camera's ability to transfer signal <u>accounting for noise</u> from sensor to output. Expressed over a range of spatial frequencies. Noise-free image DQE = 1.

Resolution (d) in object (real) space and Frequency (s) in Fourier (diffraction) space

Object space resolution: d (nm) Total sampling points in an image: N Fourier space sampling distance: Δs (1/nm) = 1/(Nd) Maximum frequency (Nyquist) in Fourier space $s_{max} = \frac{1}{2} d$

Nyquist Frequency

Nyquist-Shannon Sampling Theorem If a signal contains no information at frequencies higher than S_{max} =B, then it can be reconstructed by sampling with a frequency of $2S_{max}$ or higher



Modulation Transfer a Function of Frequency

$$M = (I_{\max} - I_{\min}) / (I_{\max} + I_{\min})$$



OUTPUT



M = 1 M = 0.7 M = 0.3 M = 0.1

Practical Assessment of CCD Using C-film Image

















Bammes *JSB* 175(3): 384-393 (2011)

Gatan 4k CCD Performance w/ 300kV

Scope Mag	Detector Mag	Pixel size	(Nyquist) ⁻¹ (Å)	(1/2Nyquist) ^{−1} (Å)	(2/3Nyquist) ^{−1} (Å)
30,000	42,000	3.57	7.14	14.29	10.71
40,000	56,000	2.68	5.36	10.71	8.04
50,000	70,000	2.14	4.29	8.57	6.42
60,000	84,000	1.79	3.57	7.14	5.37
80,000	112,000	1.34	2.68	5.36	4.02
100,000	140,000	1.07	2.14	4.28	3.21
120,000	168,000	0.89	1.79	3.57	2.67
150,000	210,000	0.71	1.43	2.86	2.13

Donghua Chen et al (2008) JSB

CCD Detector Resolution vs Magnification



Bammes et al. *JSB* 175(3): 384-393 (2011)

Sensor type plays major role in camera performance and optimization:

- CCD: Charge is transferred between neighboring cells, and "read-out" (i.e., noise) is seen at final stage: Binning minimizes impact of read-out noise.
- CMOS: Charge immediately converted to voltage (read out with digital output): Supports high frame rates, low overall electronics noise.

http://en.wikipedia.org/wiki/Active_pixel_sensor



CCDs move photogenerated charge from pixel to pixel and convert it to voltage at an output node. CMOS imagers convert charge to voltage inside each pixel.

DDD Performance with Graphite



Graphite Crystal Peak @ 1/3.35 Å⁻¹ (Nyquist Frequency)

Bammes et al (2012) *JSB* **177**:589-601.

DDD performance test with C-film





DDD performance with virus particle







DDD performance with virus particle





Epsilon15 Phage

- Vitrobot
- •JEM3200FSC
- 300 kV
- In column energy filter
- Recorded on films
- •Scanner: Nikon

Joanita Jakana at NCMI, Houston

600Å



 $\begin{array}{l} Object \ transmitted \ wave \ function \ \overline{\Psi}_0(x_o, y_o) \\ \overline{\Psi}_0(x_o, y_o) \ \approx \ 1 \ + \ i\sigma \nu(x_o, y_o) \\ \nu(x_o, y_o) \ = \ \int V(x_0, y_0, z_0) \ dz_0 \end{array}$

Object Coulomb potential function $V(x_o, y_o, z_o)$

Phase shift $\gamma(S)$ introduced by objective lens $\gamma(S) = 2\pi (\frac{1}{4}C_s \lambda^3 S^4 - \frac{1}{2} \varDelta Z \lambda S^2)$

Diffraction wave function $\bar{\Psi}_d(S_x, S_y)$ $\bar{\Psi}_d(S_x, S_y) = F(S_x, S_y) \exp(i\gamma(S))$ $F(S_x, S_y) = \mathcal{F}[\bar{\Psi}_o(x_o, y_o)]$ Diffraction intensity $I_d(S_x, S_y) = \bar{\Psi}_d(S_x, S_y) \bar{\Psi}_d^*(S_x, S_y)$

Image wave function $\underline{\Psi}_{i}(x_{i}, y_{i})$ $\underline{\Psi}_{i}(x_{i}, y_{i}) = \mathcal{F}^{-1} [\underline{\Psi}_{d}(S_{x}, S_{y})]$ Image intensity $I_{i}(x_{i}, y_{i})$ $I_{i}(x_{i}, y_{i}) = \delta(0, 0) - 2\sigma \nu(x_{i}, y_{i}) * \mathcal{F}^{-1} [sin \gamma(S)]$

Computed diffraction wave function $T(S_x, S_y)$ $T(S_x, S_y) = \mathcal{F} [I_i(x_i, y_i)]$ $= \delta(0, 0) - 2 F(S_x, S_y) \sin \gamma(S)$



Individual Sine Curves









Sum of All Three Curves



Data Quality Assessment: Computed FFT of Particle Images



Joanita Jakana

1.04µm defocus

Computed Diffraction Pattern

F²(s) CTF²(s) Env²(s) + N²(s) Structure factor Contrast transfer function

Saad et al *JSB* **133**: 32-42 (2001)

X ray Scattering Intensity of GroEL



Ludtke et al (2001) J Mol Biol 314, 253-262

Computed diffraction pattern $F^{2}(s)$ (CTF²(s) Env²(s) + N²(s) Structure factor Envelope function Background Contrast transfer function

Contrast Transfer Function

CTF (s) = - A [(1-Q²)^{1/2} sin(γ) + Q cos(γ)] γ (s) = - 2 π (C_s λ^3 s⁴/4 - Δ Z λ s²/2)

 ΔZ is vector dependent if there is an astigmatism

CTF Simulation - Microsoft Internet Explorer								
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CTF Simulation Publication: Web-based Simulation for Contrast Transfer Function and Envelope Functions. Microscopy and Microanalysis 7(4), 329-334, 2001								

Contrast of an ectron image is influenced by the contrast transfer function (CTF) and the envelope functions of the electron microscope. In order to plan an experimental condition for data collection or to interpret the contrast of an electron micrograph, one would often need to know the quantitative values of these functions for a given set of microscope parameters. This simulation program is written in <u>lava</u> applet and <u>lavaScript</u> programming language. The parameters of these functions can be adjusted interactively with slider bars and the plot for the simulated function would be updated instantaneously.

This applet is known to run on Windows (Netscape and Internet Explorer), Linux (i386) (Netscape), SGI IRIX (Netscape), OS/2 Warp and MacOS X. Please inform me if you found that this applet runs or has problems to run on other platforms.

The following is the detailed descriptions for some aspects of the applet page.

List of the special symbols/functions used in the applet

Term	Unit	Description	
S	1/Å	resolution	
ν	keV	accelerating voltage	
Cs	mm	spherical aberration	
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CTF Simulation - Microsoft Internet Explorer - [Working Offline] _ 8 × <u>File Edit View Favorites Tools Help</u> Voltage(keV) 1/s = 10 A xmin f(s) = 0.1172 300 0 10.8 Cs(mm) xmax 0.2 1.6 -0.4 Cc(mm) ymin -1 2.2 г.

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0.9	<u> </u>		.]]						
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Enter a function f(s), which can use the varibles(s,v,a,dZ,B,Cs,Cc,Q,dE,dl,dF,dR):

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Voltage(keV) 300 Cs(mm) 1.6 Cc(mm) 2.2 Energy spread(eV) 0.9 Lens current spread(ppm) 1 Vertical motion(Angstrom) 50 Drift(Angstrom) 0	1/s = 10 A f(s) = 0.2142 -0.8 -0.4 -0.4 0.4 0.4	0.06	0.08	0,1	0.12	0.14	0.16	0.18		xmin 0 xmax 0.2 ymin -1 ymax 1 Set Limits Restore Limts
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B(angstrom^2) 📕									•	100
Amp Contrast									•	0
Angle(mrad) 📕									×	0.1
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↓										

Jiang & Chiu Microsc. and Microanal. 7:329-334 (2001)

Computed diffraction pattern $F^{2}(s) CTF^{2}(s) Env^{2}(s) + N^{2}(s)$ Structure factor Envelope function Background Contrast transfer function

EM Envelope Functions : Env(s) Gaussian type source: $G_{sc}(s) = \exp[-\pi^2 \alpha^2 (C_s \lambda^2 s^3 - \Delta Z s)^2]$ Gaussian type fluctuation:

$$G_{tc}(s) = \exp\left[-\frac{\pi^2}{16\ln 2}C_C^2\lambda^2\left(\frac{\Delta E}{E}\right)^2s^4\right]$$

Gaussian type fluctuation:

$$G_{ol}(s) = \exp\left[-\frac{\pi^2}{4\ln 2}C_C^2\lambda^2\left(\frac{\Delta I}{I}\right)^2s^4\right]$$

Sinusoidal type fluctuation:

$$G_{lm}(s) = J_O(\pi \Delta f \lambda s^2)$$

Drift:

$$G_{tm}(s) = \frac{\sin(\pi s \Delta r)}{\pi s \Delta r}$$

Spatial Coherence Envelope Function

 $\Delta Z=0.5 \mu m$



Spatial Frequency (1/Å)

Power Spectrum of Images of C-Film



Astigmatism

Vibration

Gaussian Approximation for Cumulative Envelope Function

$Env^2(s) \sim exp(-2Bs^2)$

Computed diffraction pattern



Noise Function

 $N^{2}(s) = n_{1} \exp(n_{2} s + n_{3} s^{2} + n_{4} s^{\frac{1}{2}})$

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Application



1/5.00 S (1/A)

1/6.67

1/4.00

0.5

1/10.00





Astigmatism

